

Docket No. MAIKP131US

IT601US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re **PATENT** application of:

Applicant: Teng-Wang Huang et al.

Application No.: 10/814,570

For: PROCESS FOR ETCHING A SUBSTRATE

Filing Date: March 31, 2004

Examiner: Duy-Vu Nguyen Deo

Art Unit: 1765

RESPONSE TO OFFICE ACTION DATED APRIL 16, 2007

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir or Madam:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following amendments and remarks.